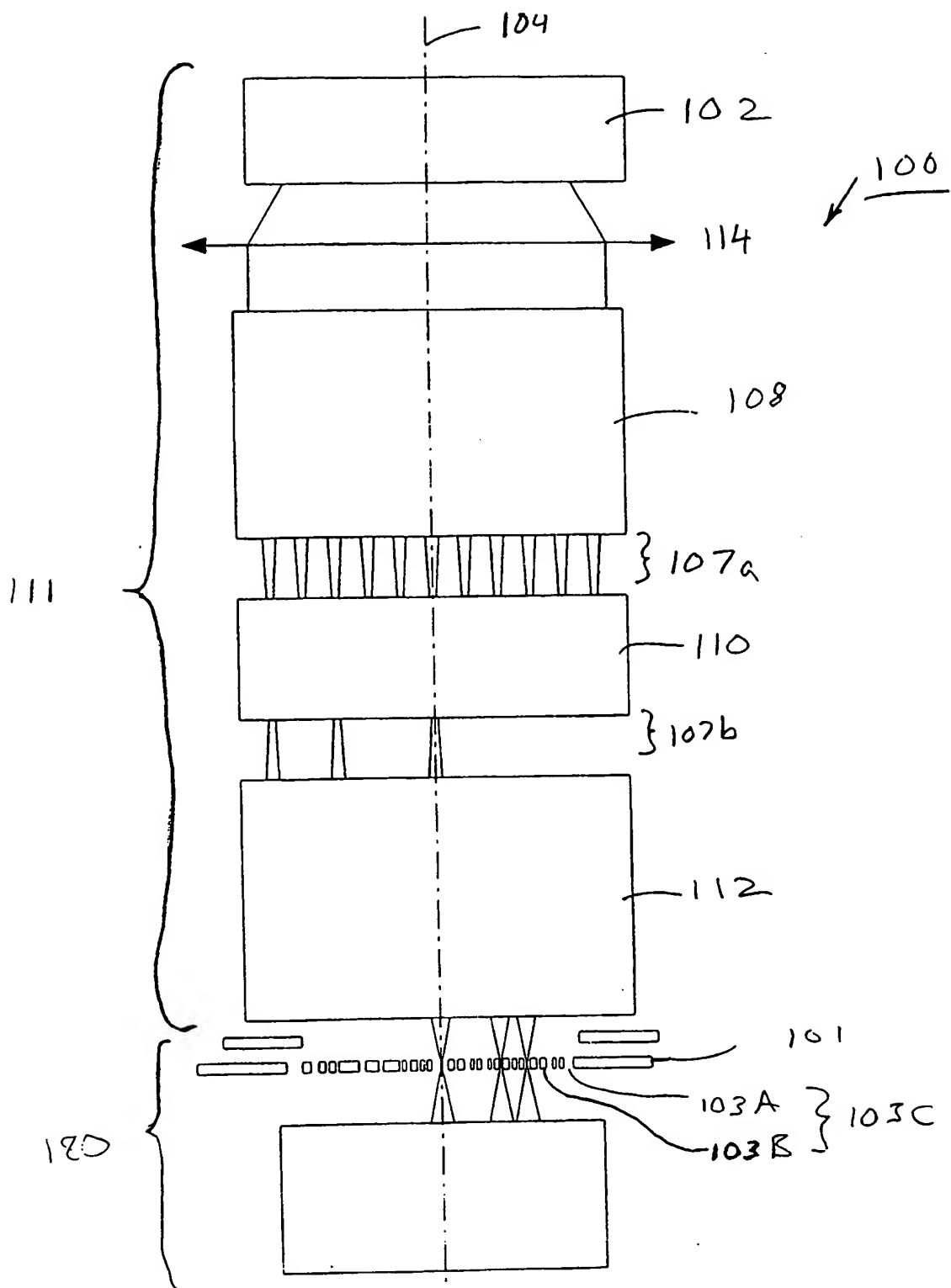
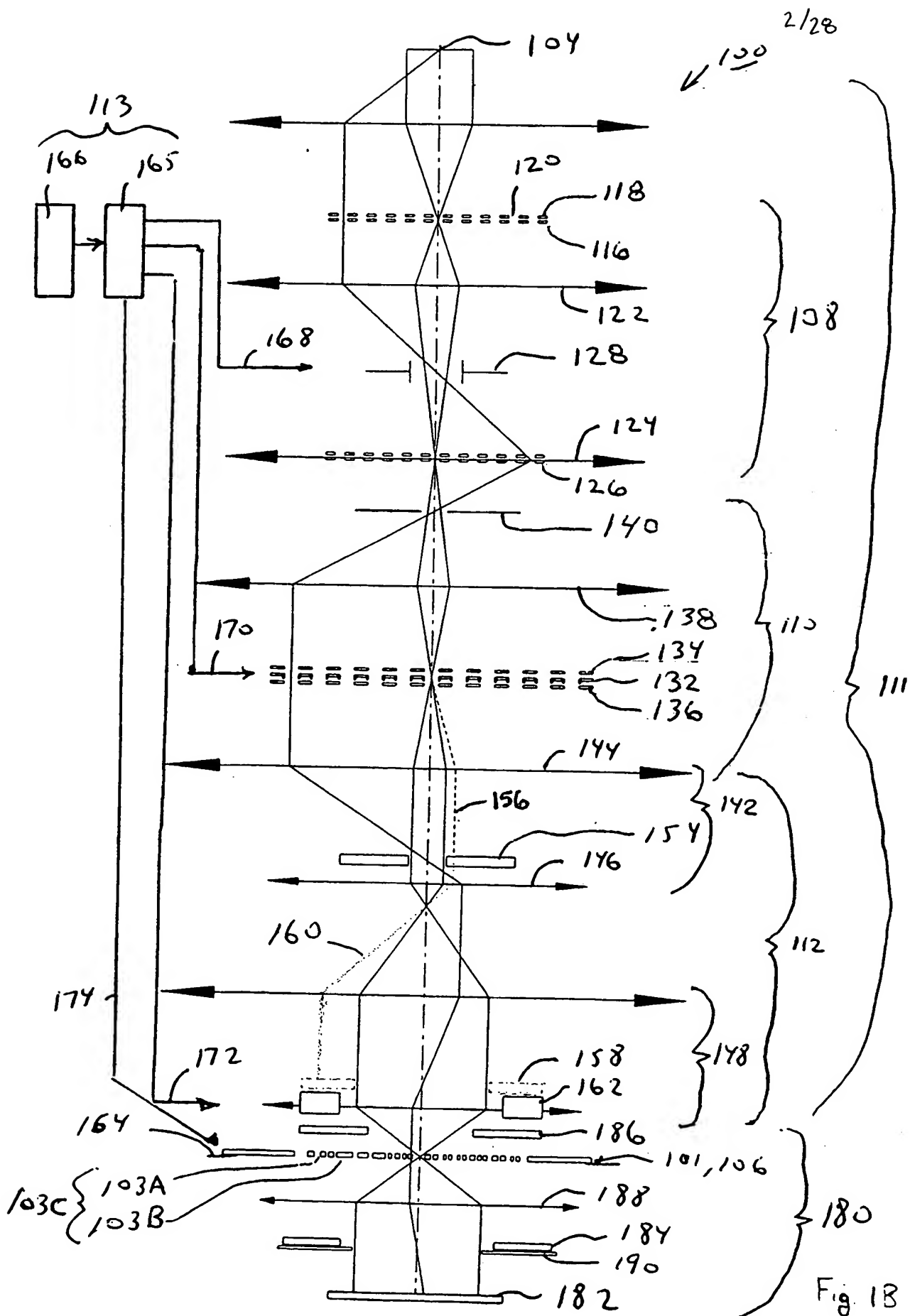


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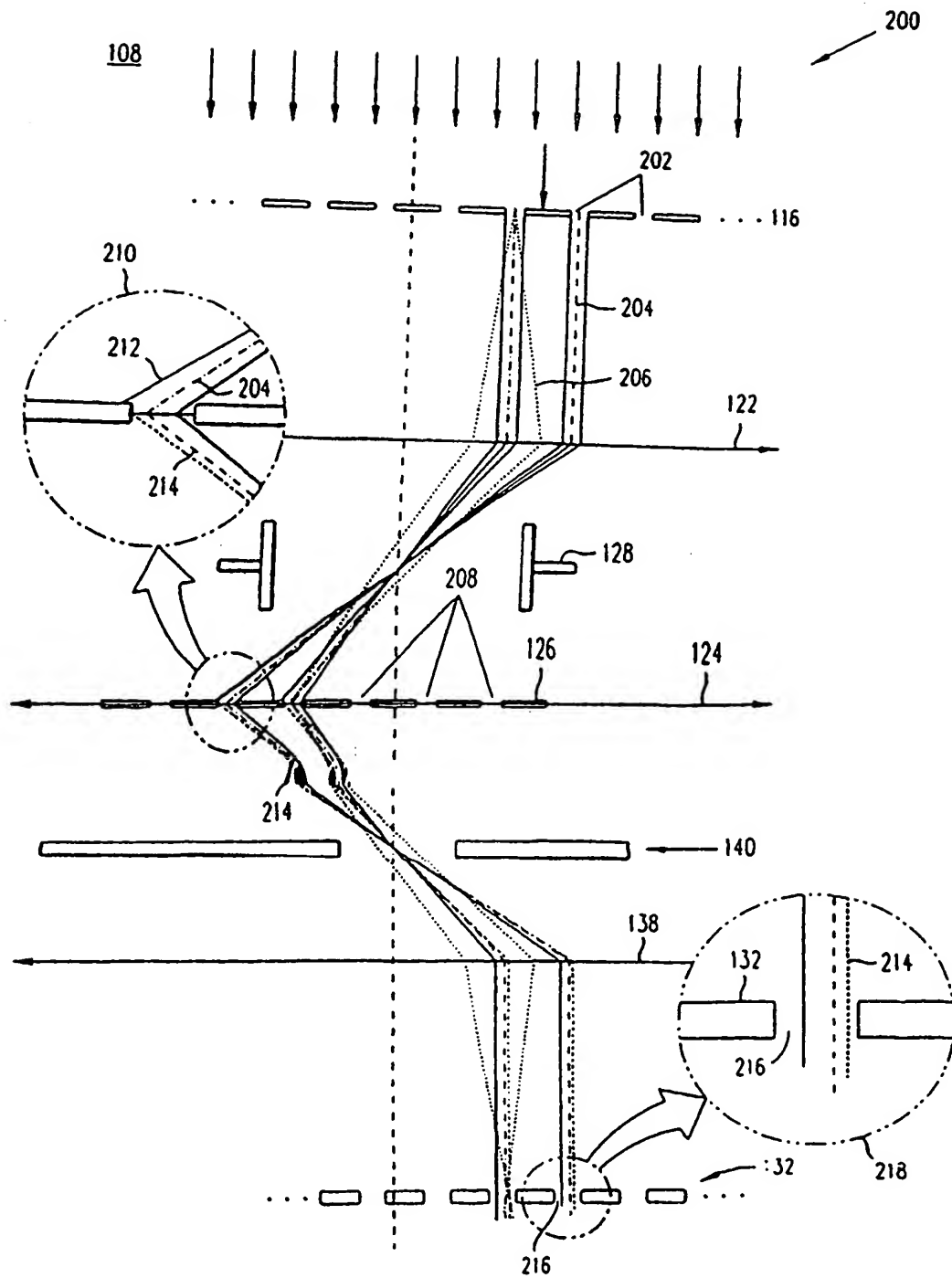


FIG. 2

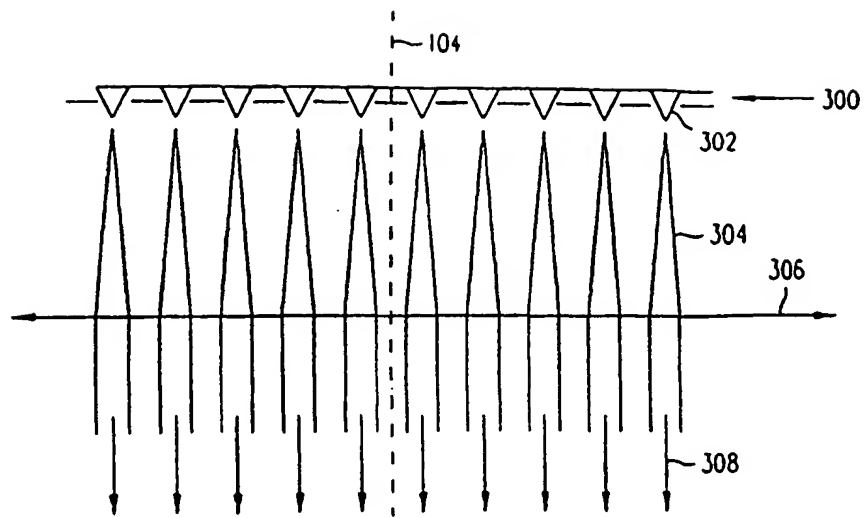


FIG. 3A

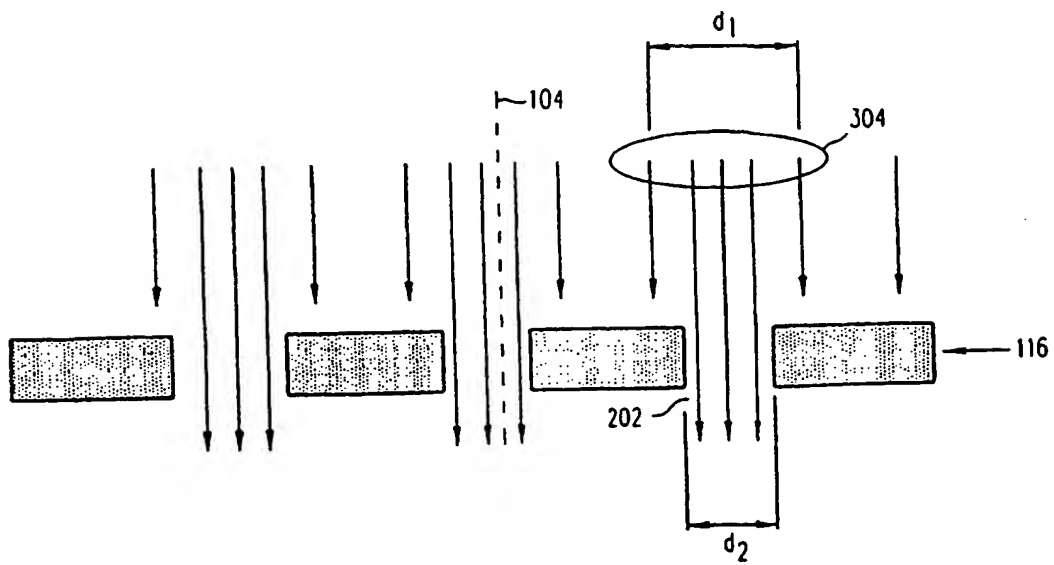


FIG. 4

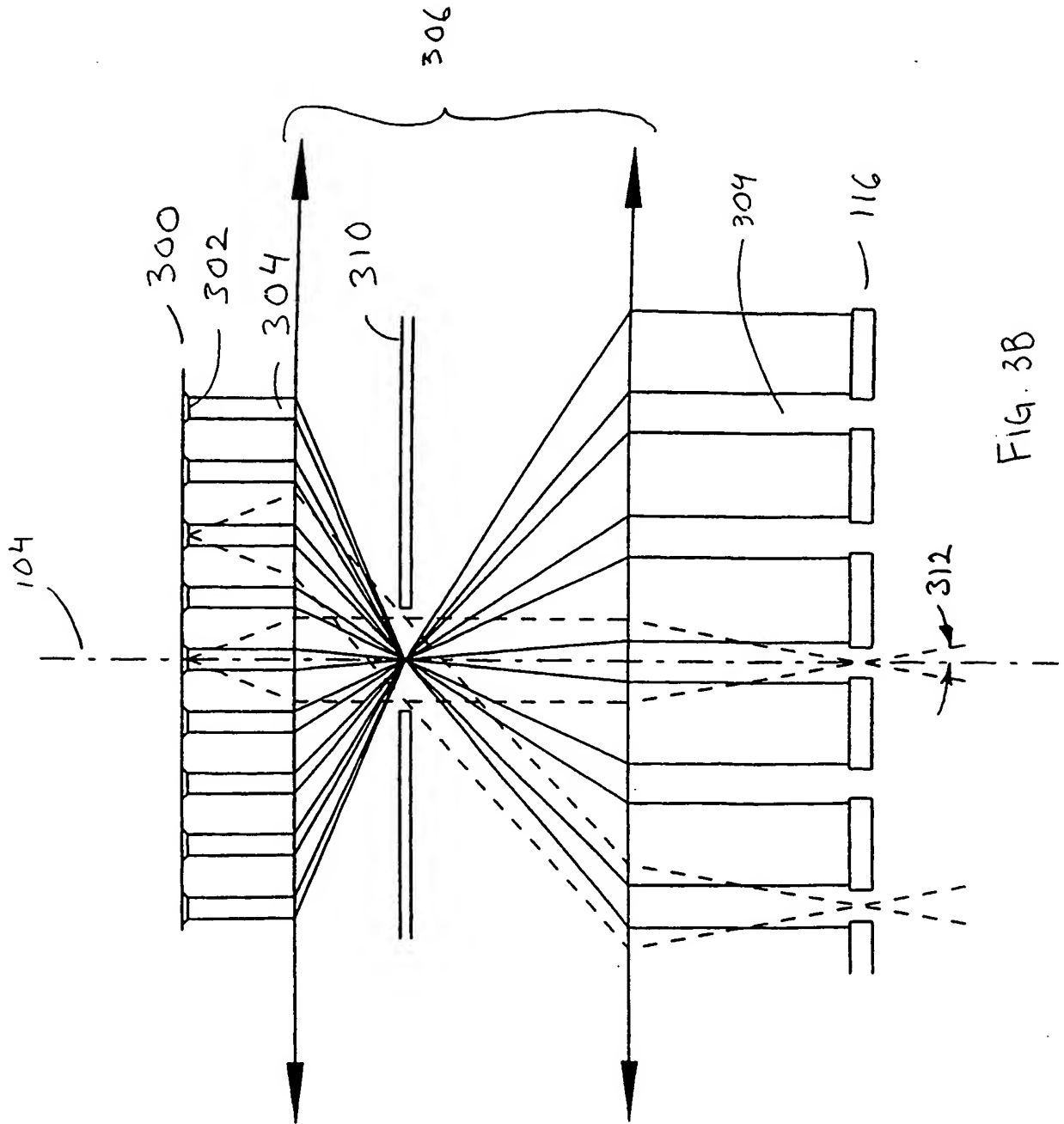


FIG. 3B

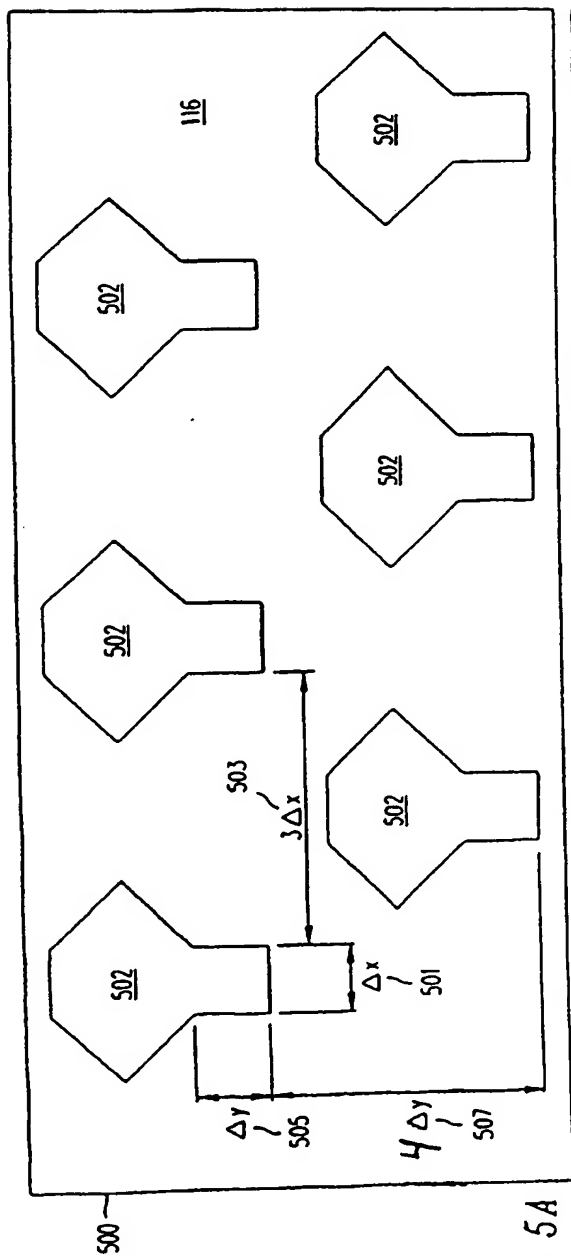


FIG. 5A

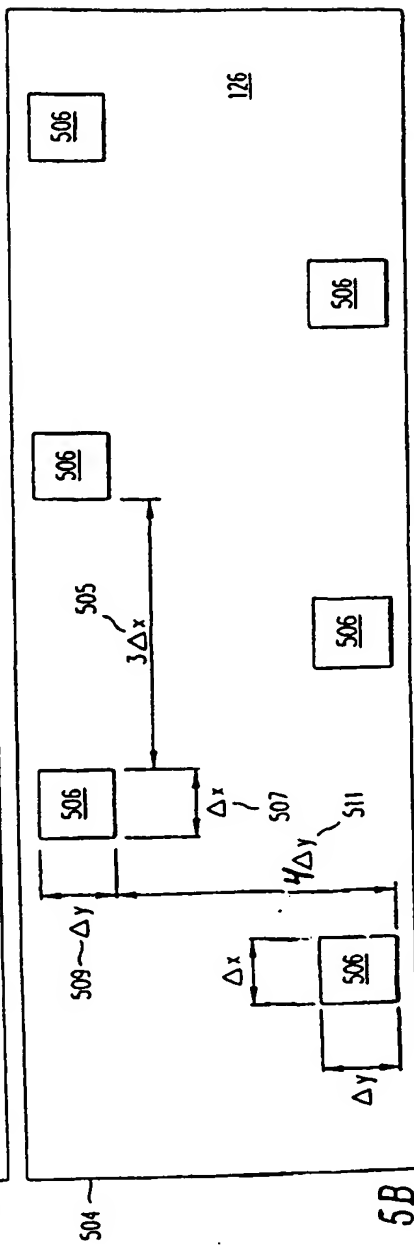


FIG. 5B

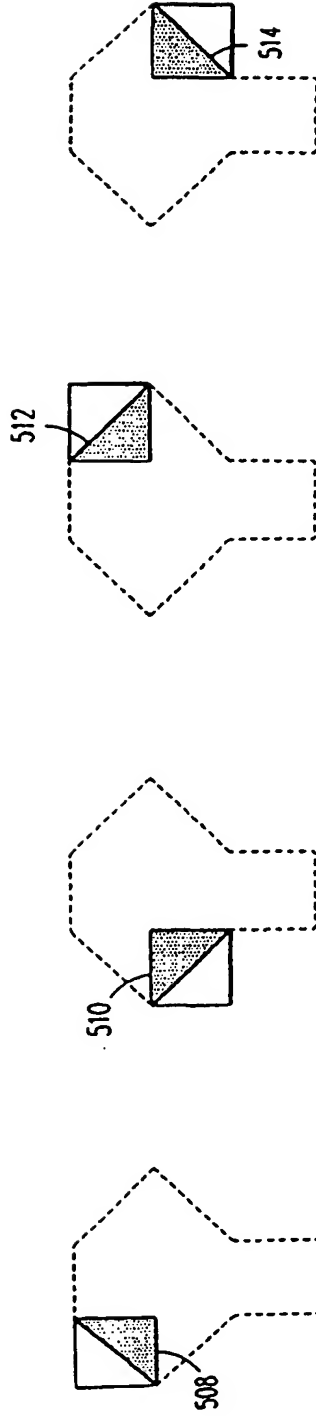


FIG. 5C

FIG. 5D

FIG. 5E

FIG. 5F

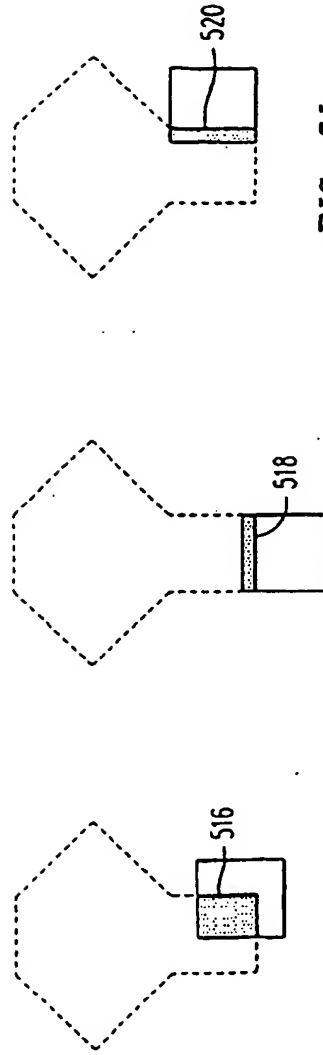


FIG. 5G

FIG. 5H

FIG. 5I

FIG. 6

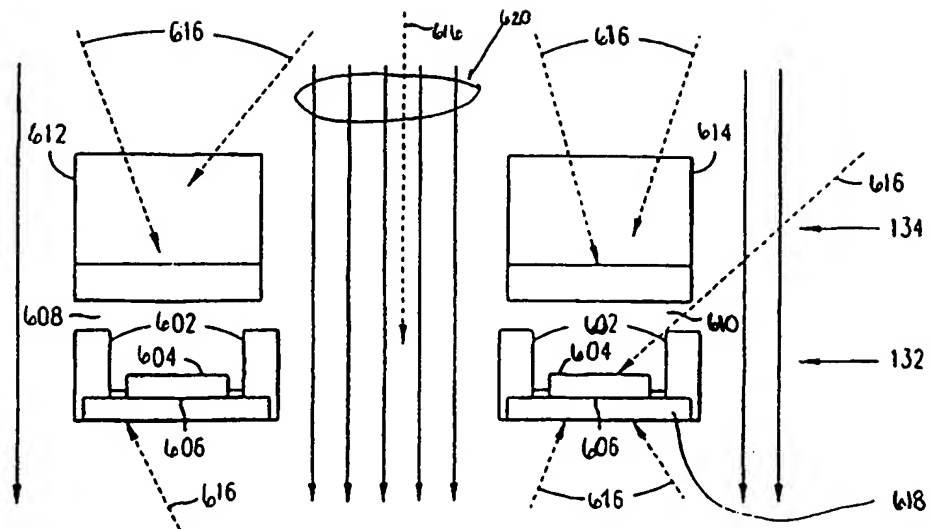


FIG. 6

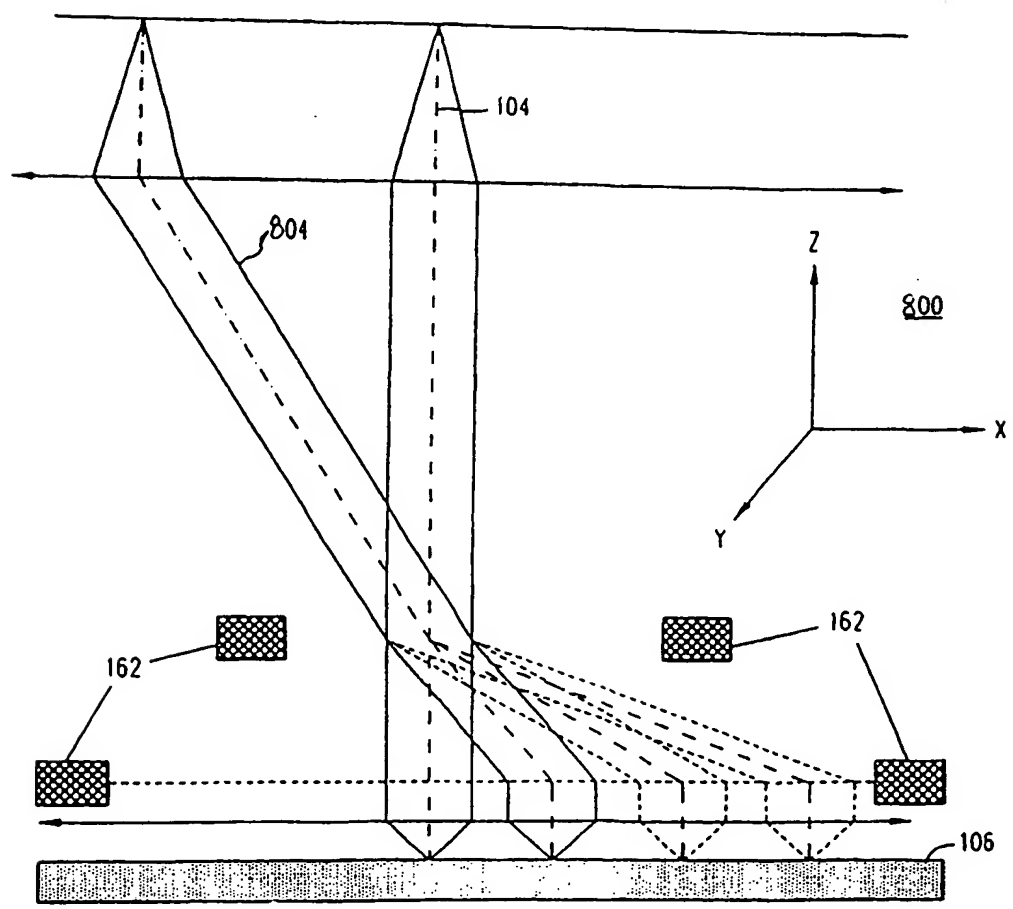


FIG. 8

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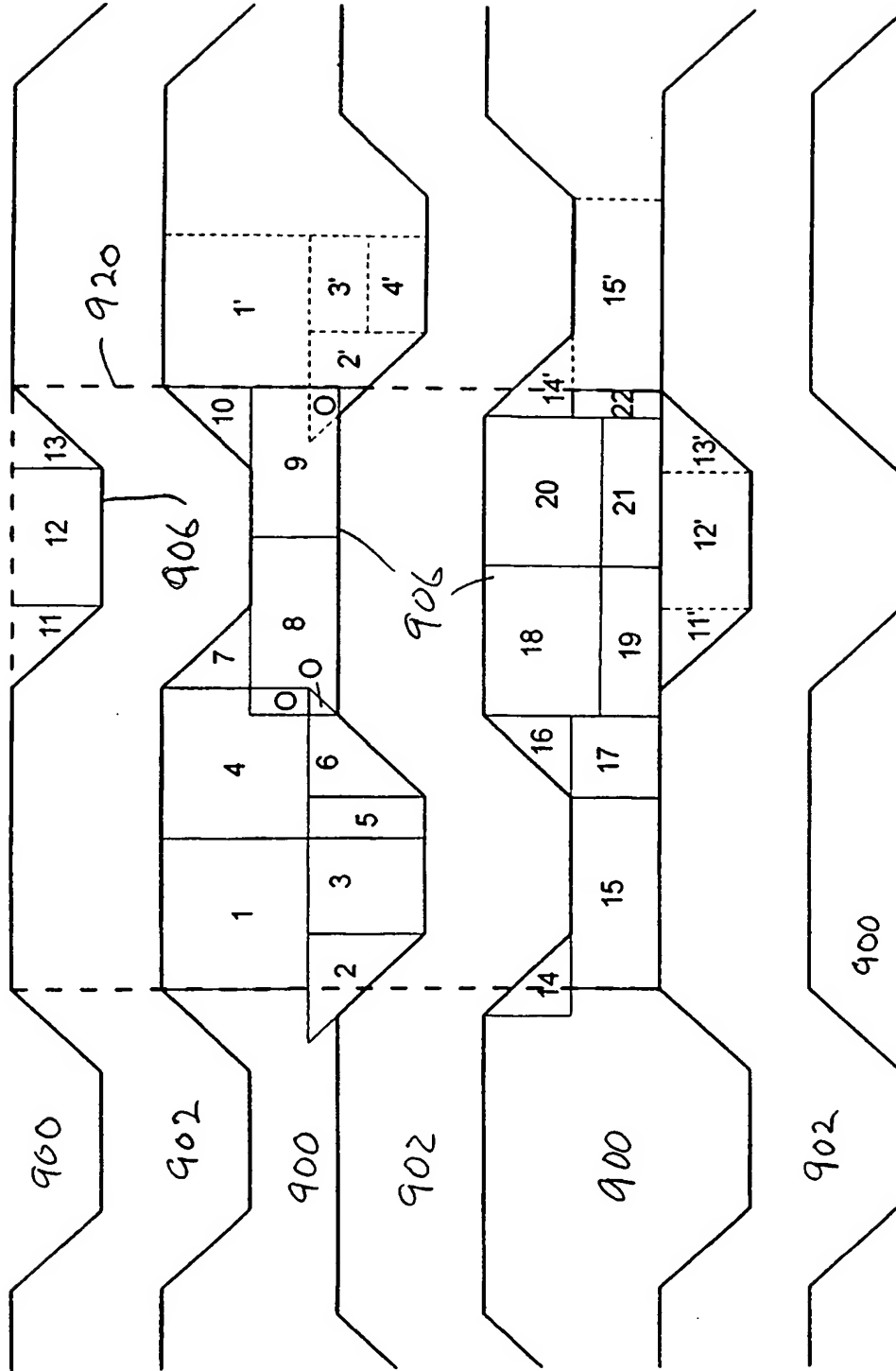


Figure 9A

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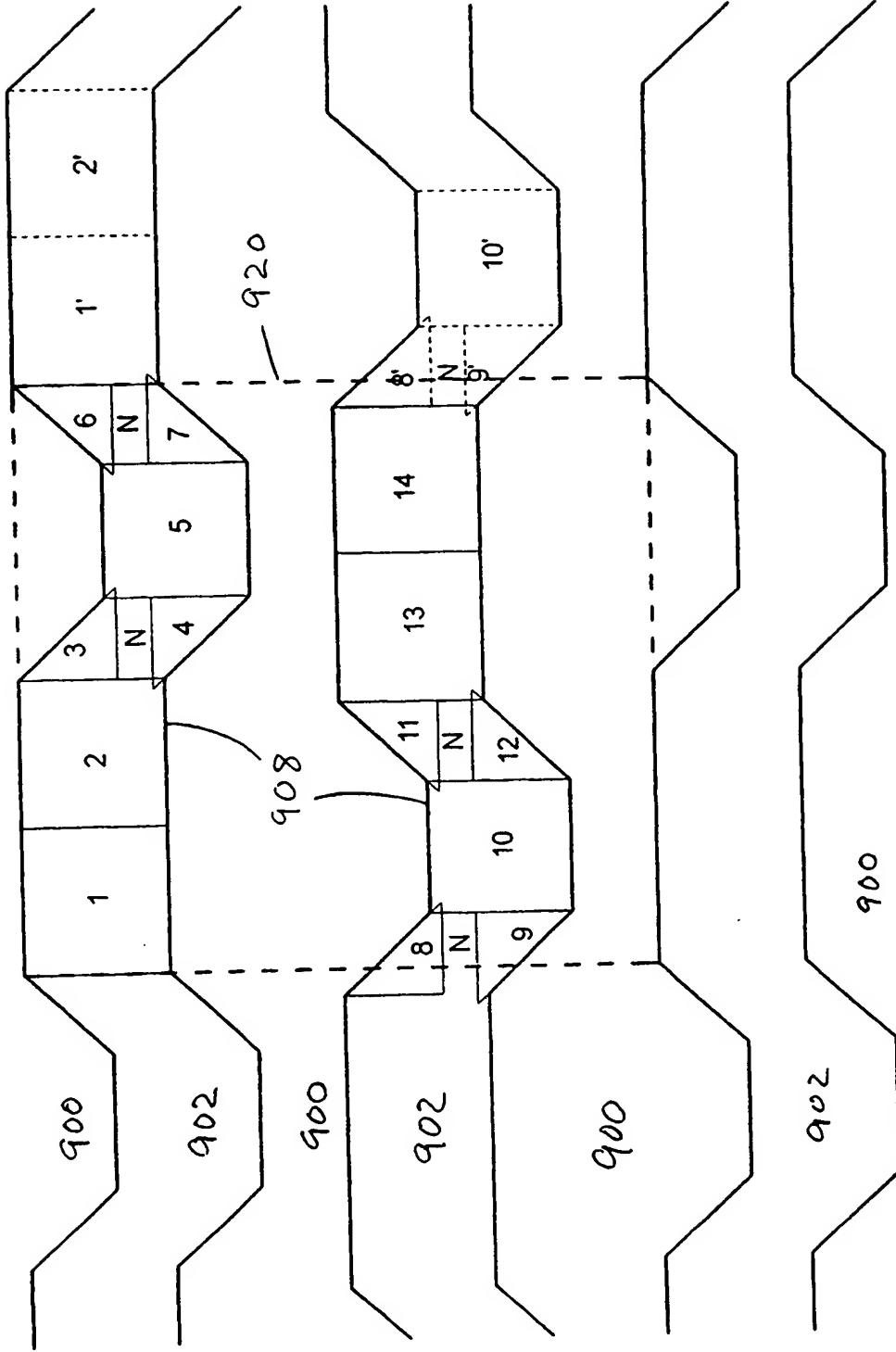


Figure 9B

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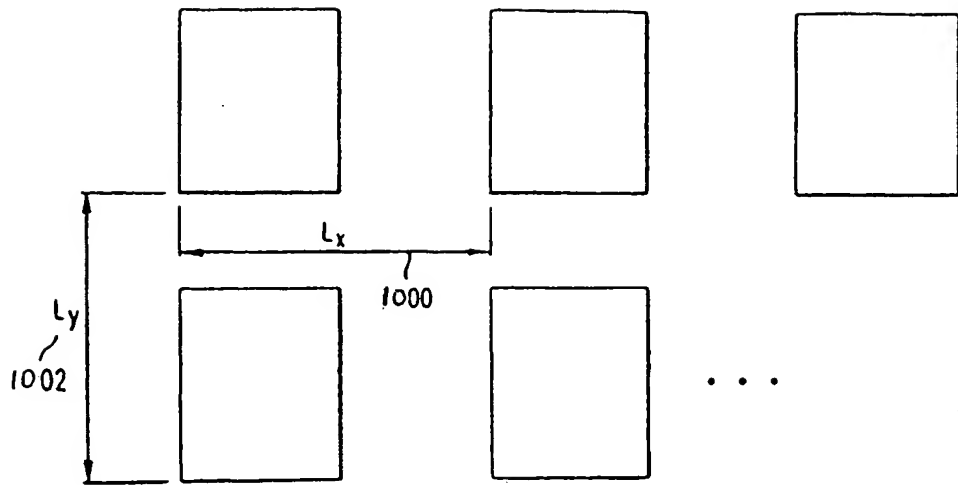


FIG. 10A

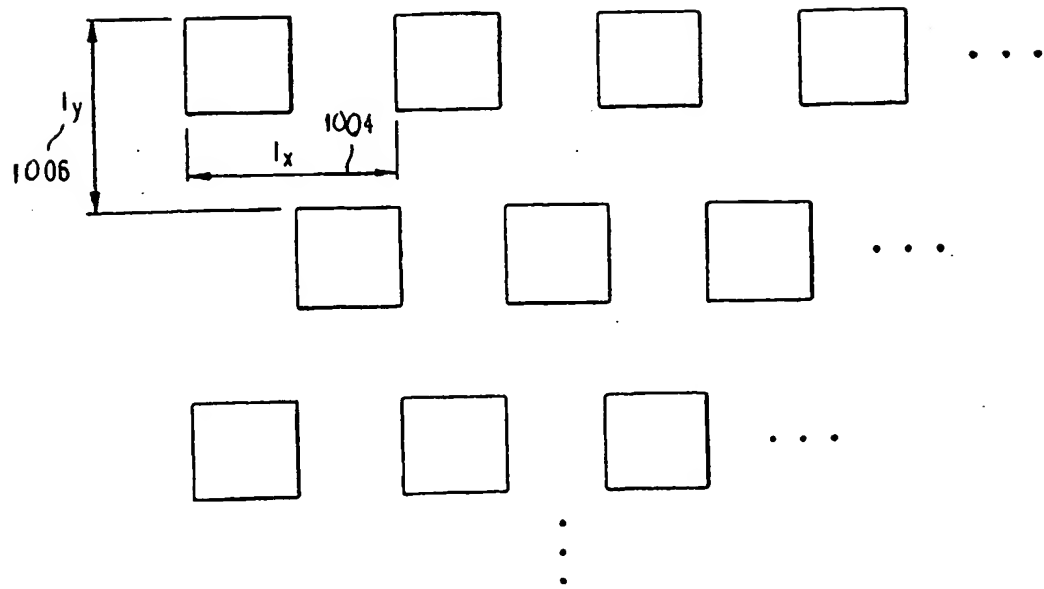


FIG. 10B

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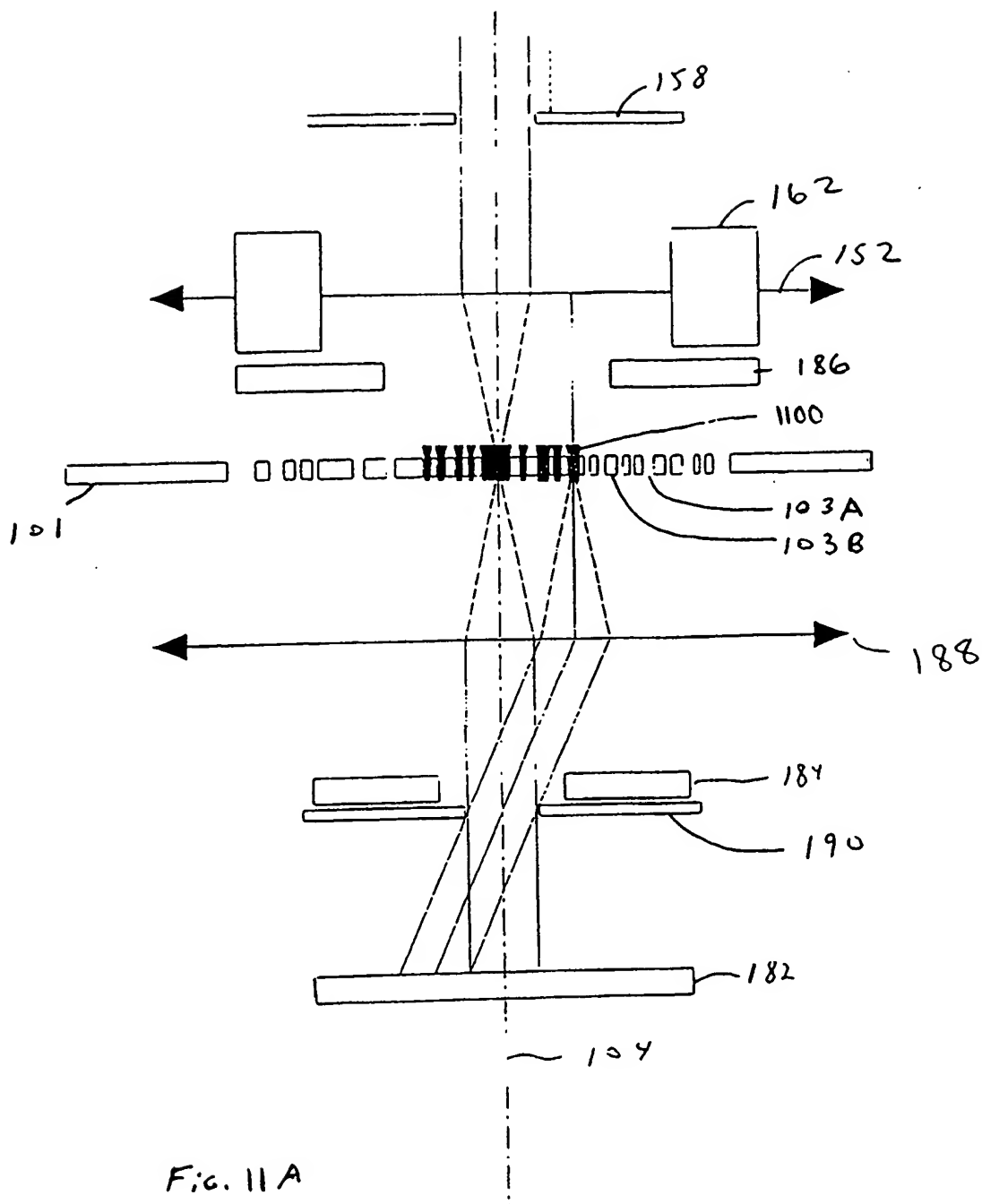


Fig. 11A

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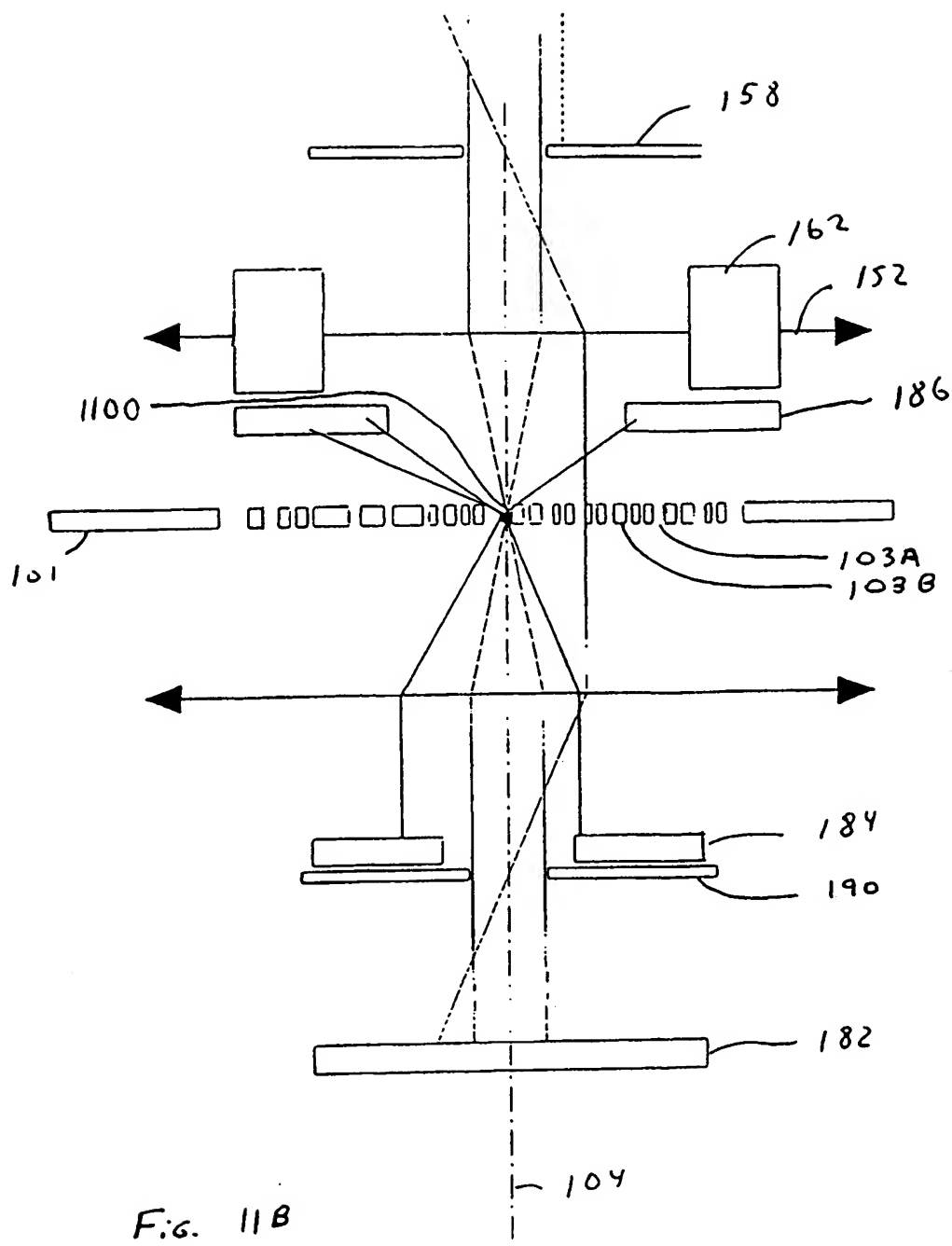


Fig. 11B

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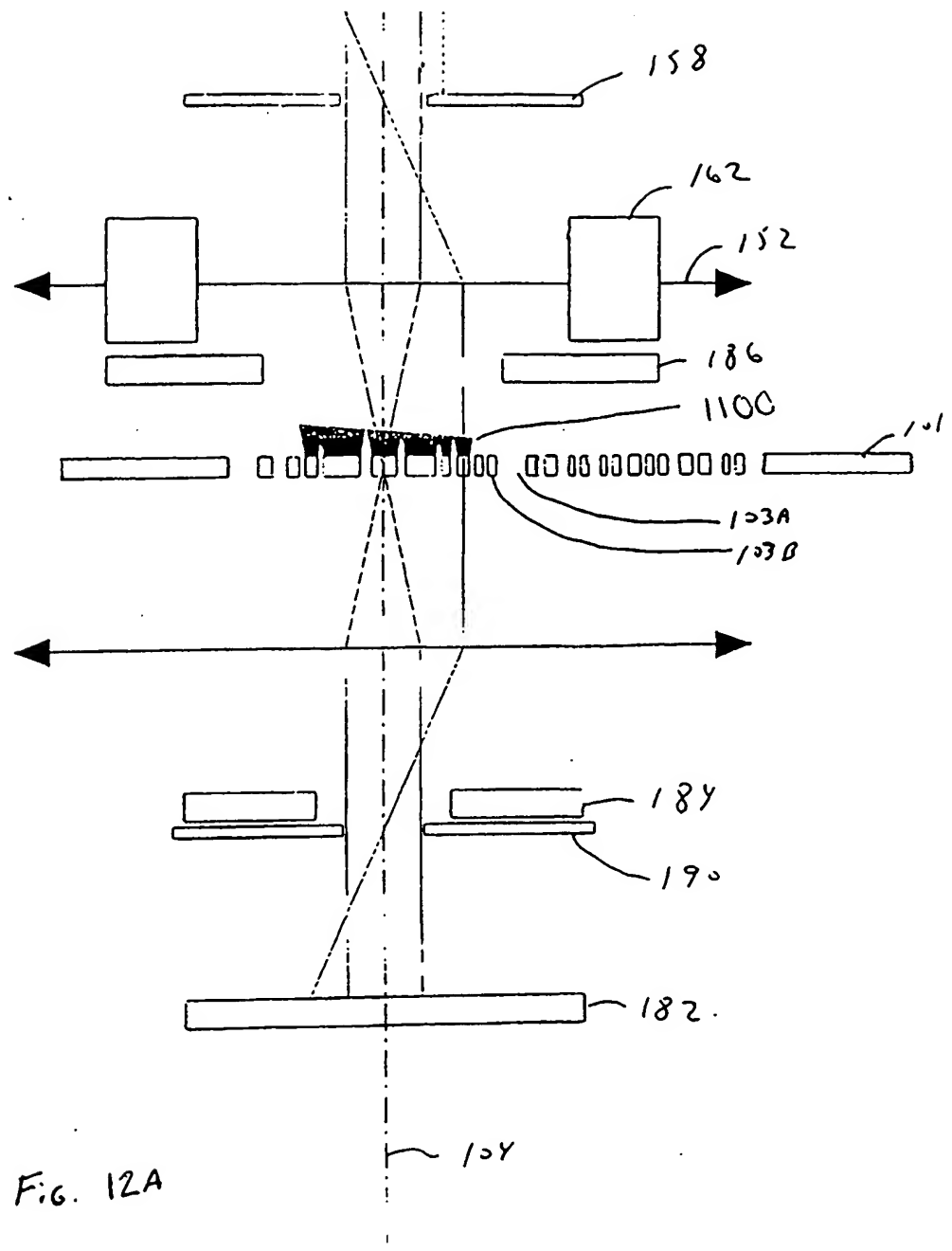


FIG. 12A

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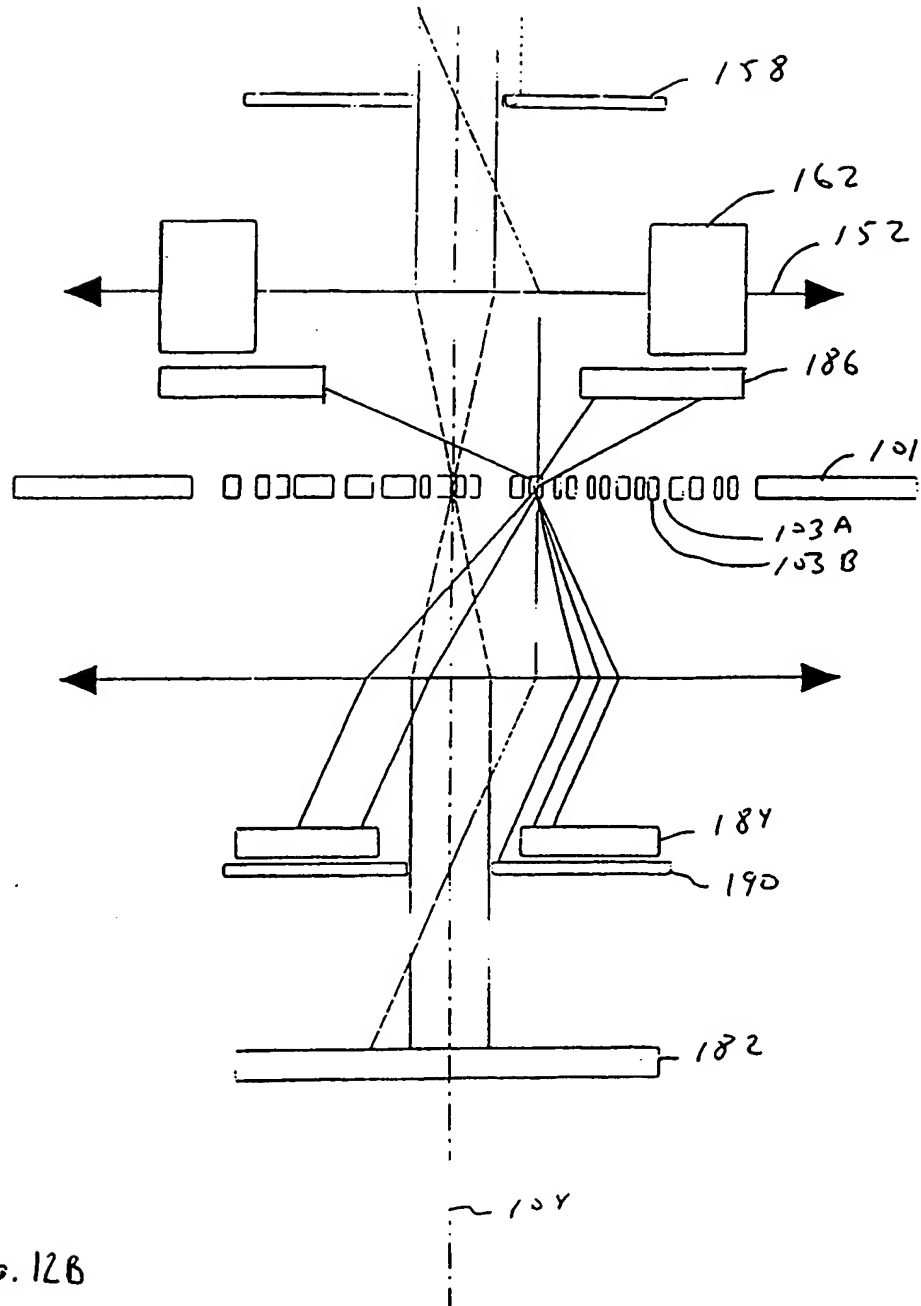


Fig. 12B

Stencil Mask Defect Detection

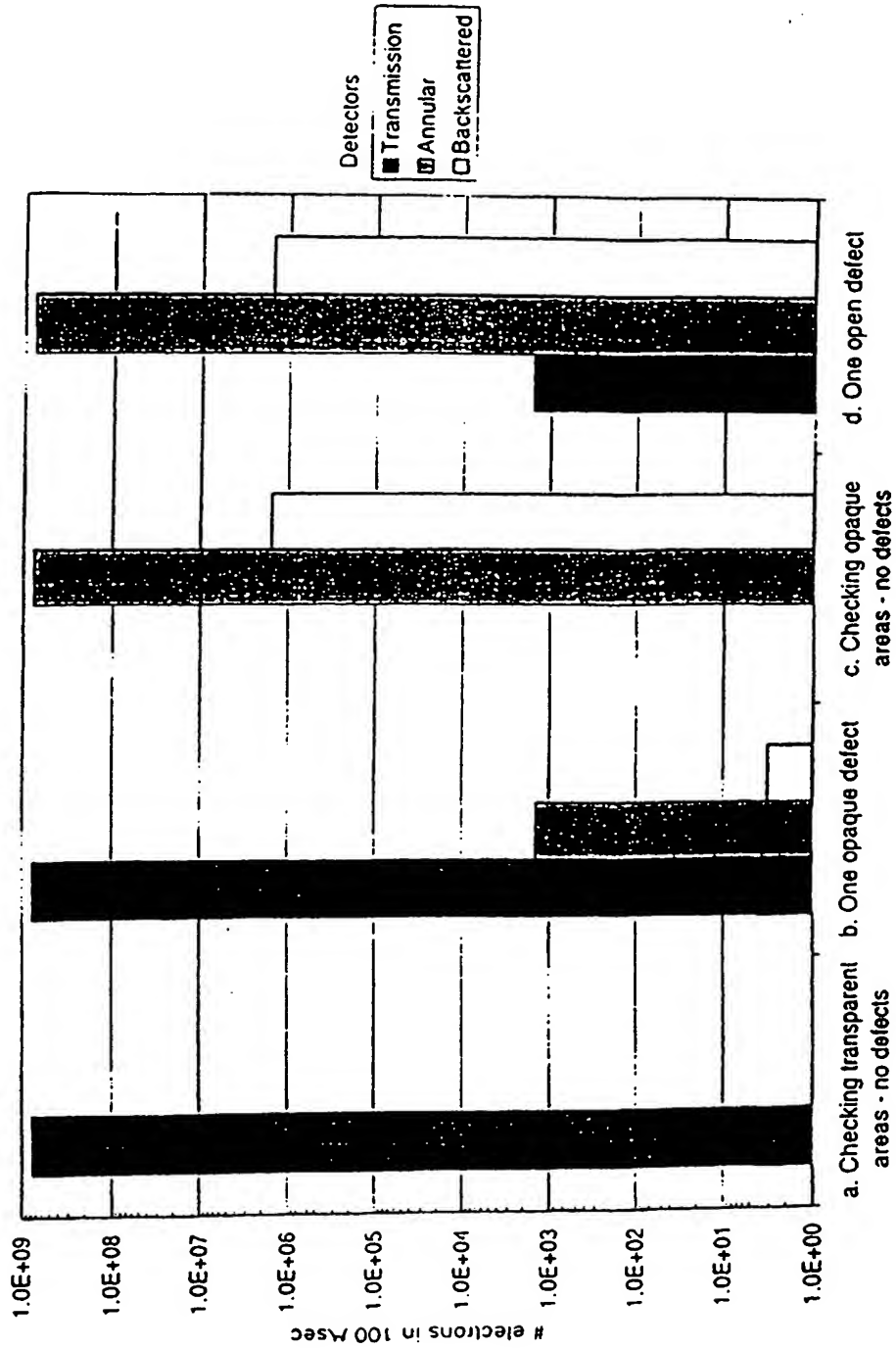


FIG. 13

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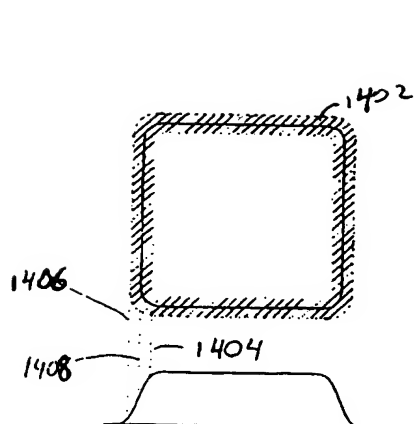


FIG. 14A

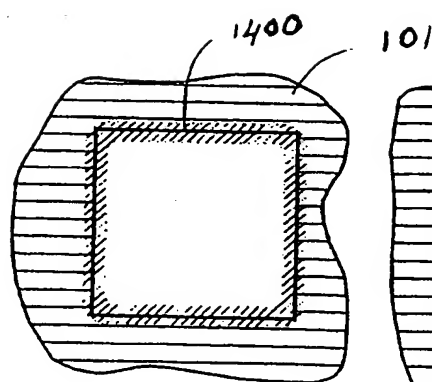


FIG. 14B

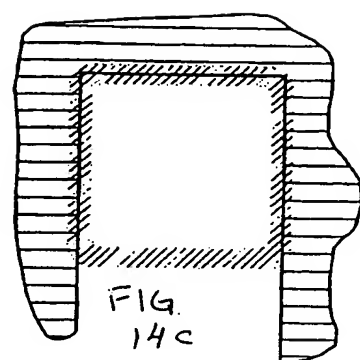


FIG. 14C

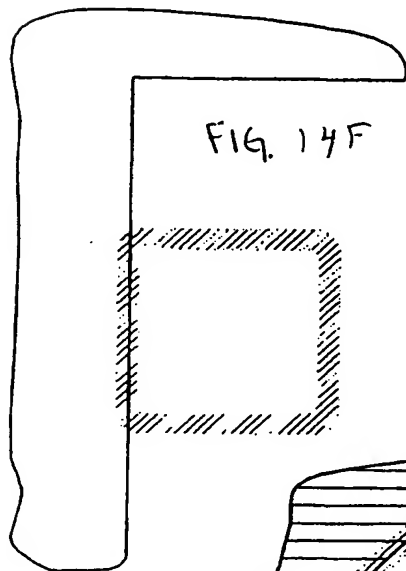


FIG. 14F

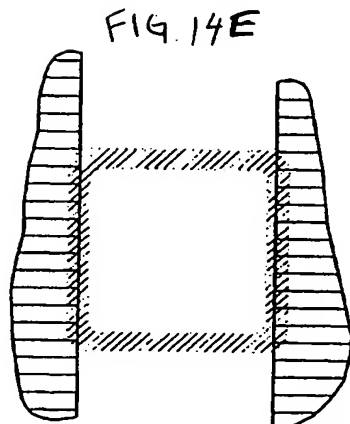


FIG. 14E

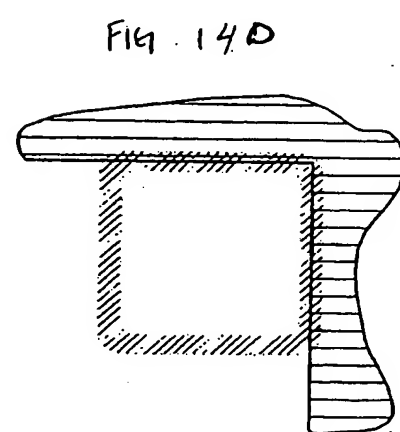


FIG. 14D

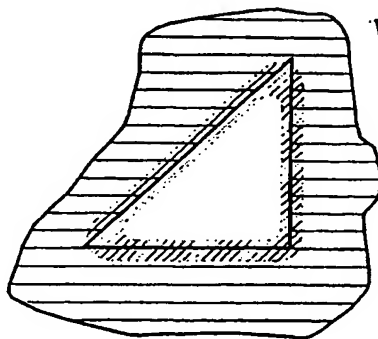


FIG. 14G

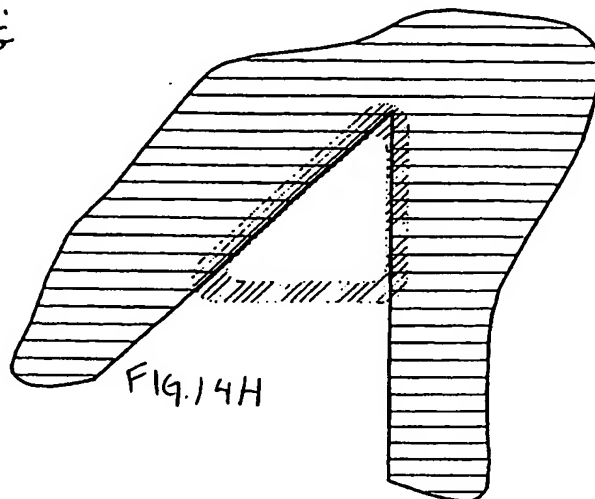


FIG. 14H

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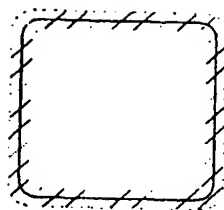


FIG.
14 I

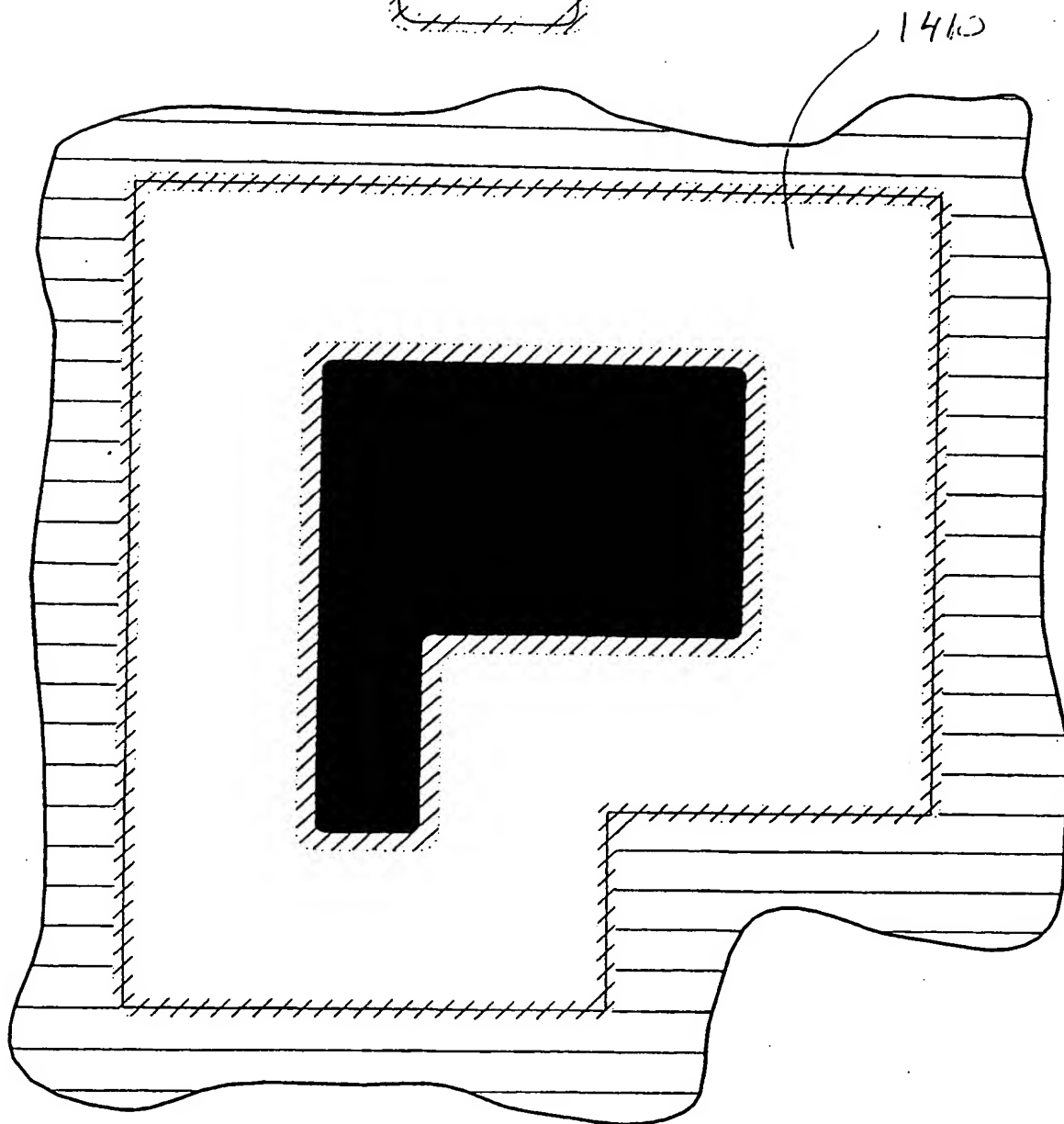


FIG. 14 J

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Fraction of beamlet lost on mask (on all four sides)
edgewidth (12/88) = 30 nm; $1\sigma = 12.77$ nm

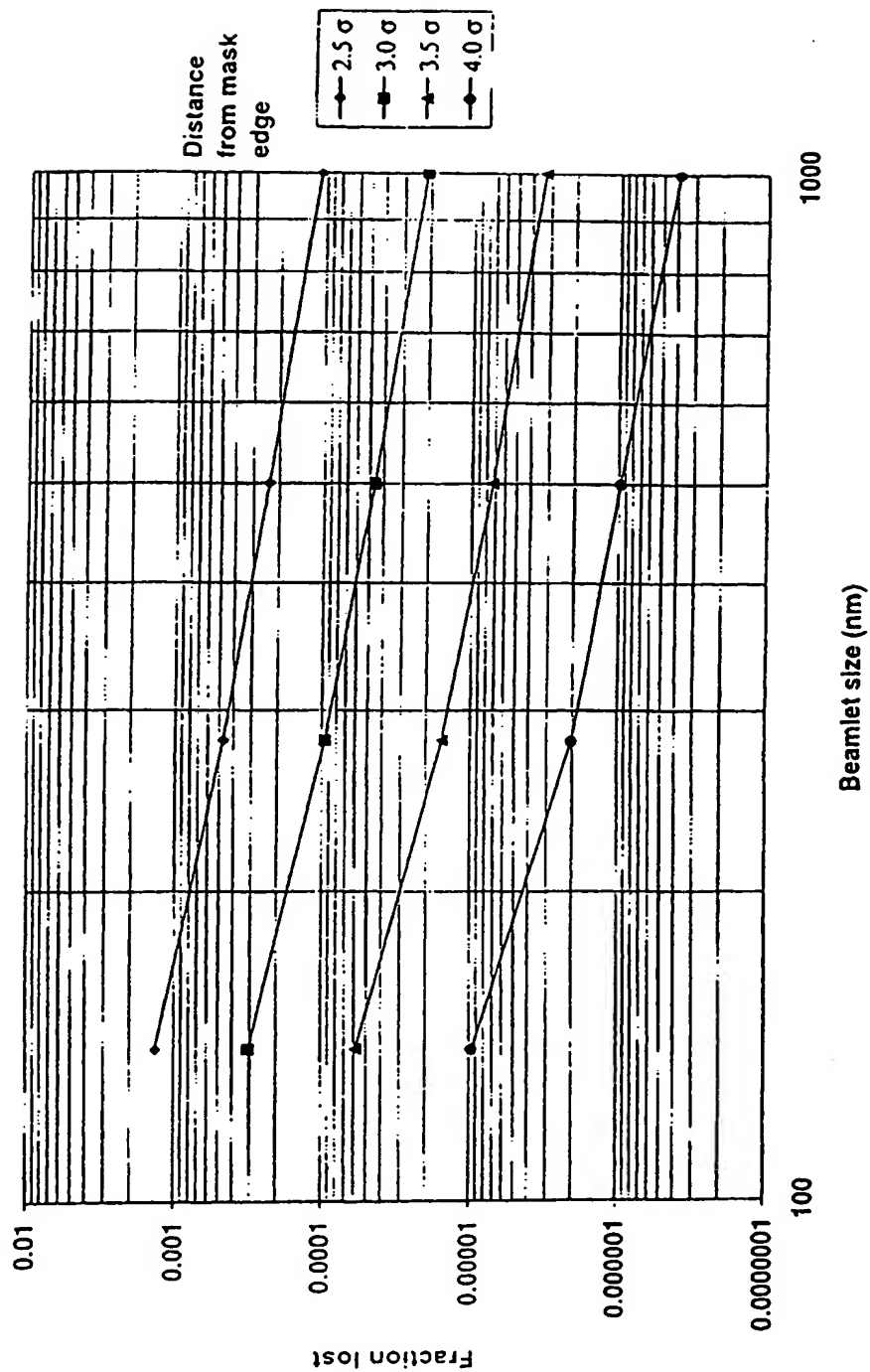
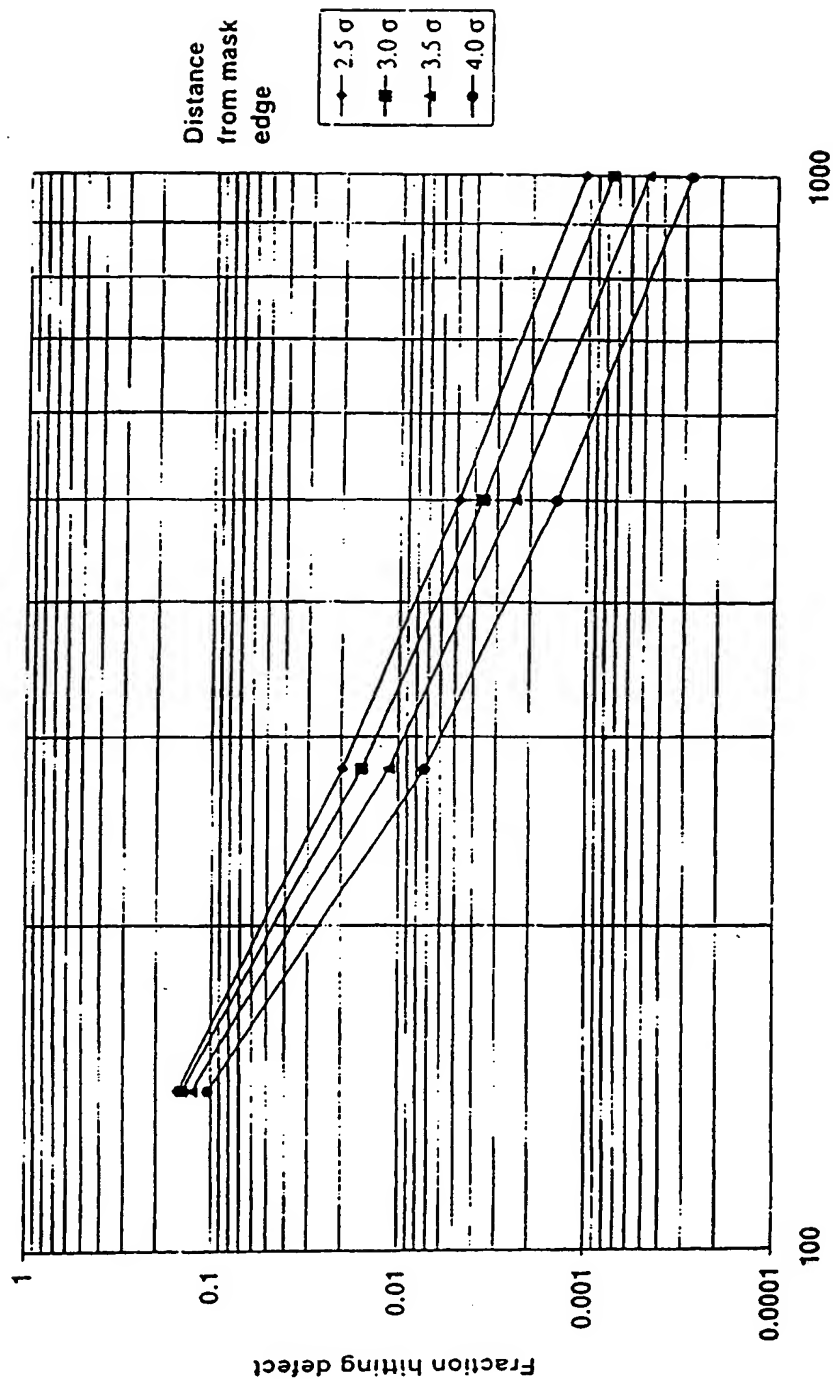


Fig. 15A

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Fraction of beamlet hitting 50 nm defect
edgewidth (12/88) = 30 nm; $1\sigma = 12.77$ nm



Beamlet size (nm)

Fig. 158

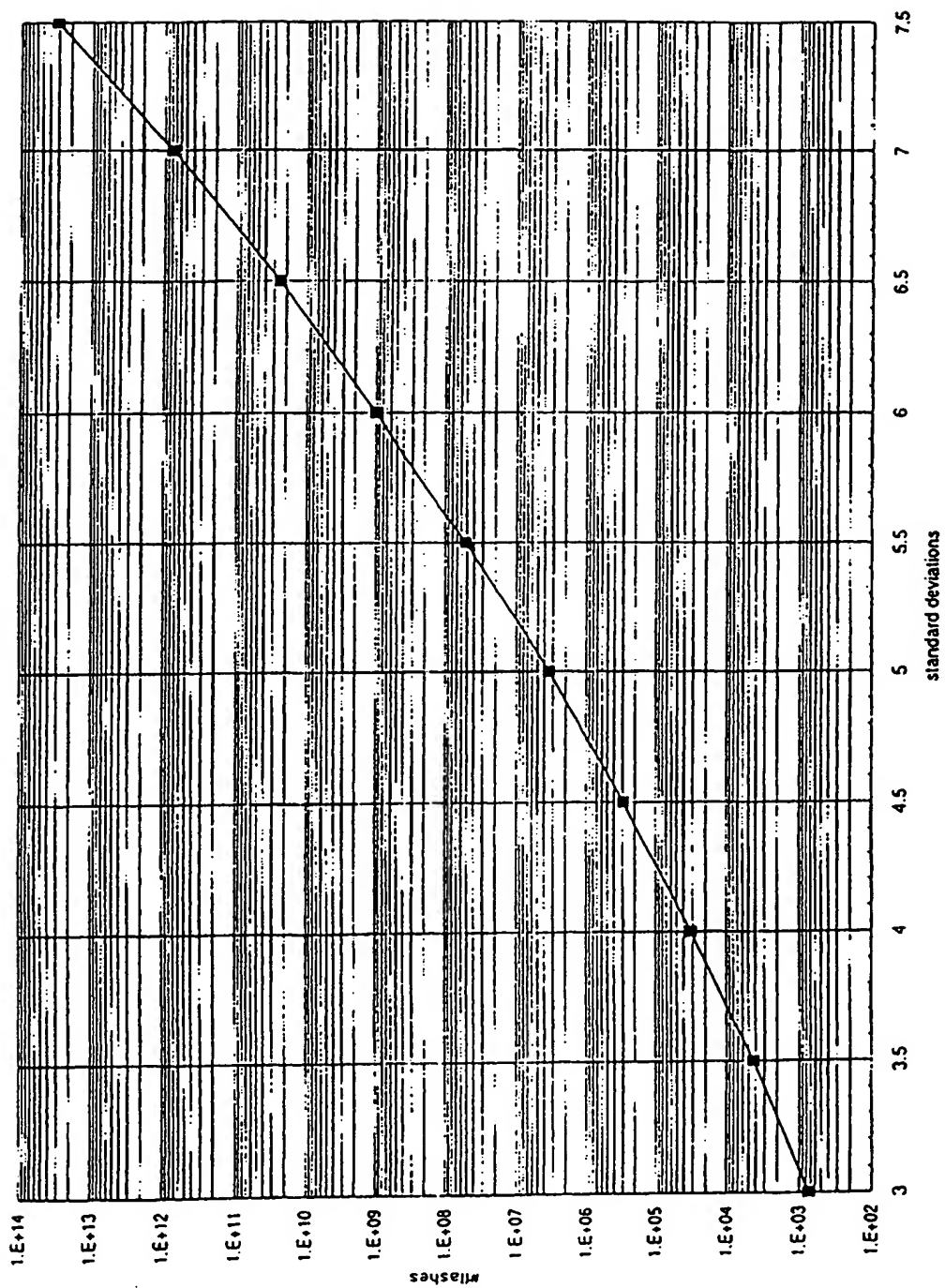


Fig. 15C

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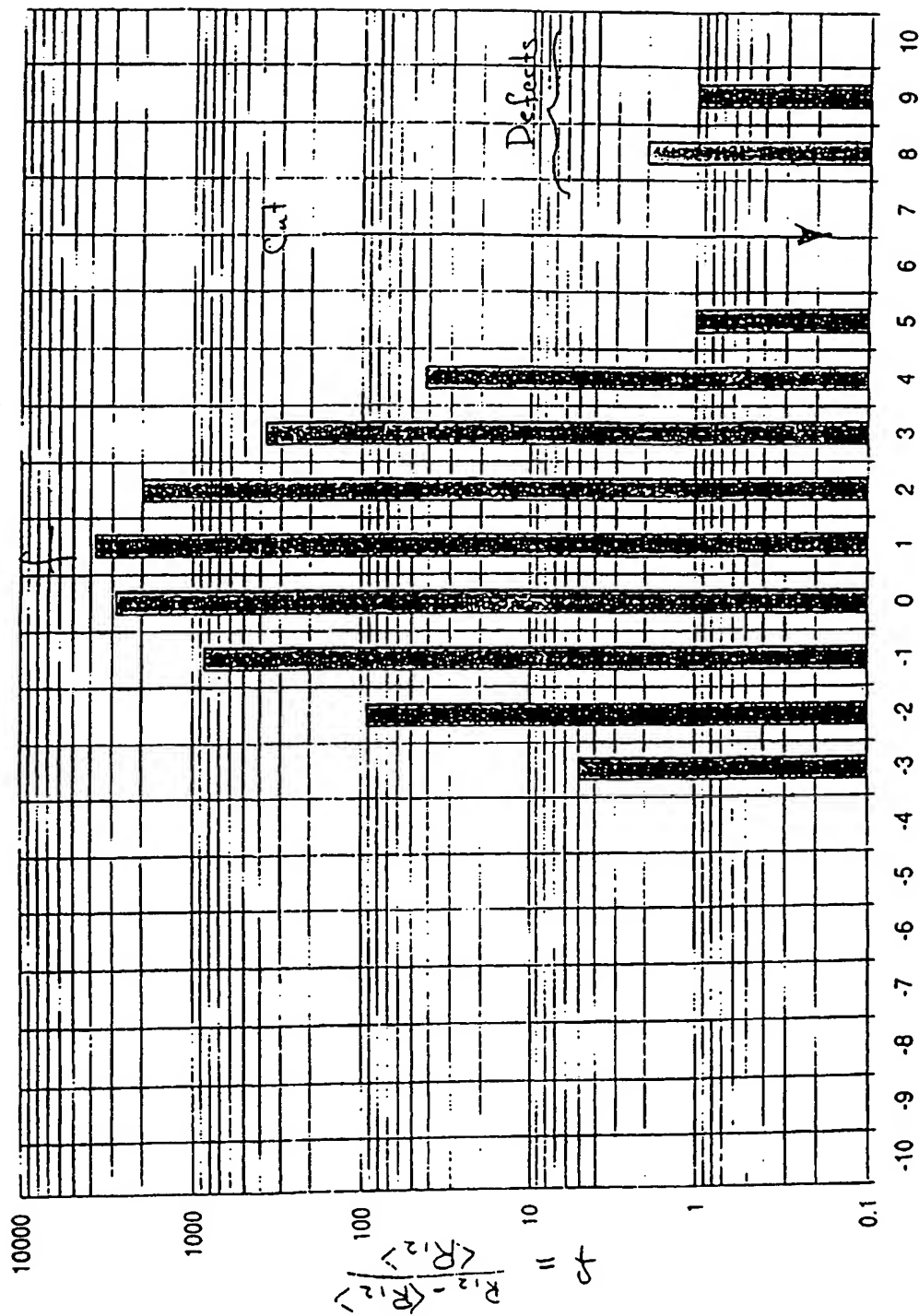


Fig. 150

f/df for clear and opaque defects

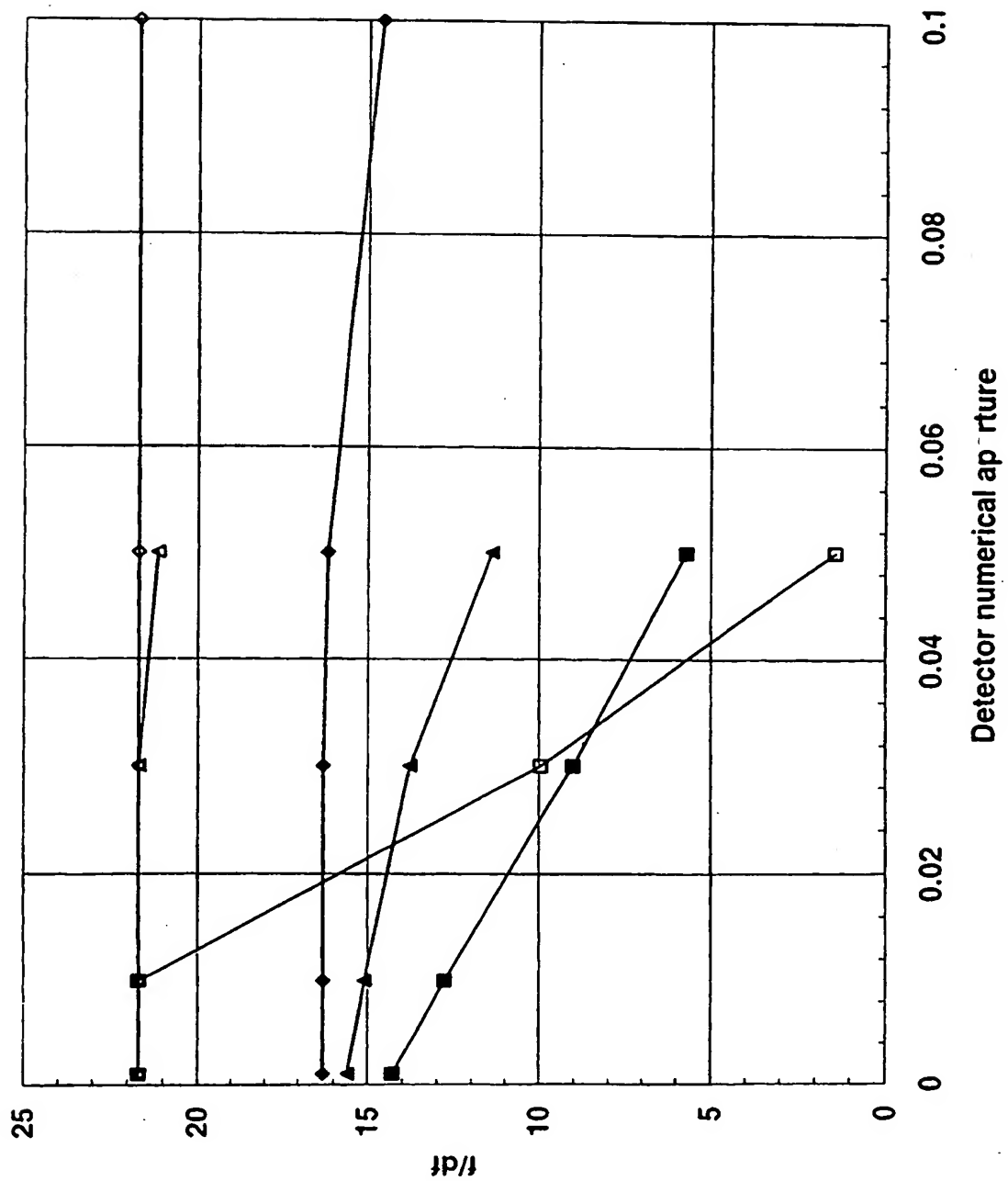
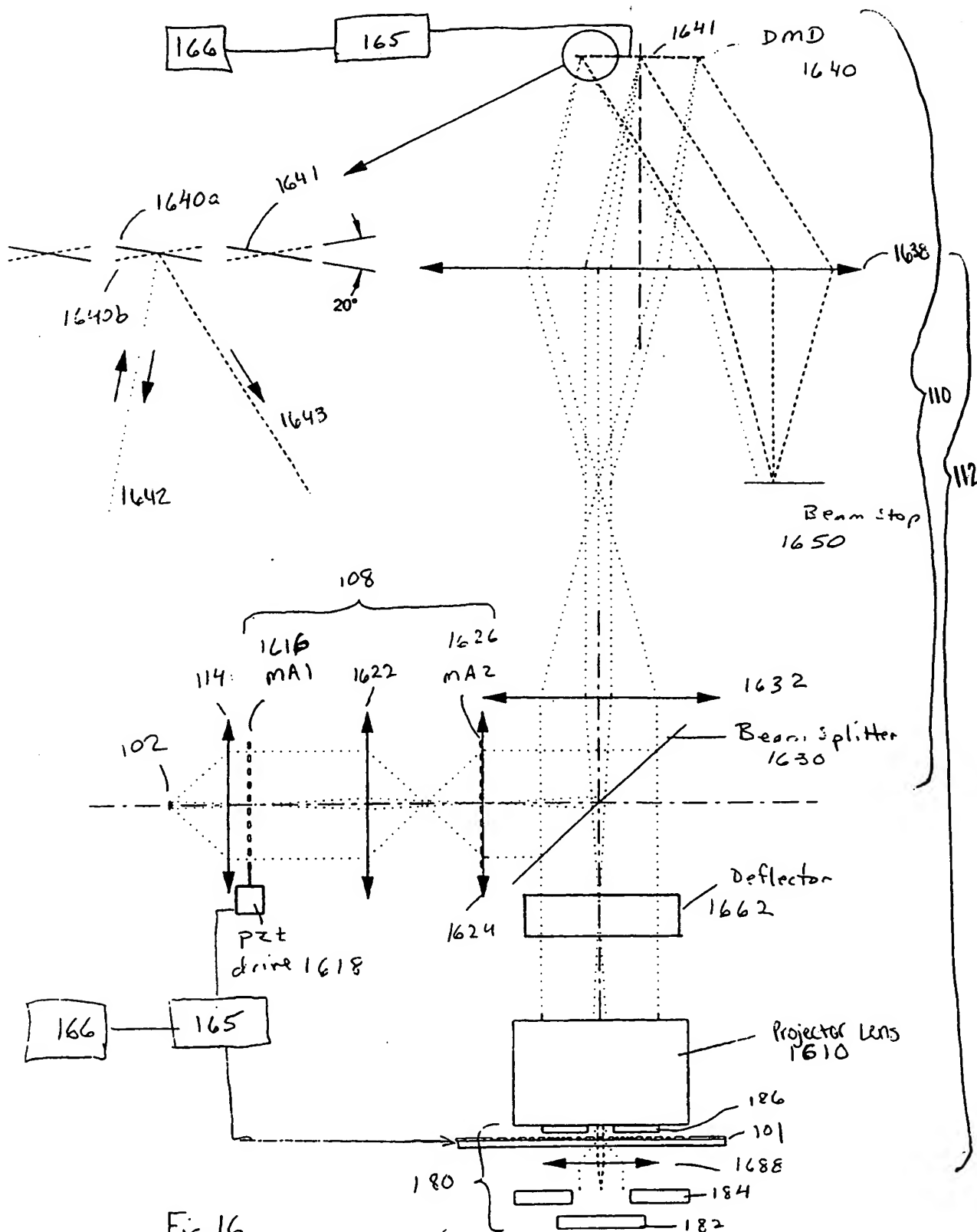


FIG 15E



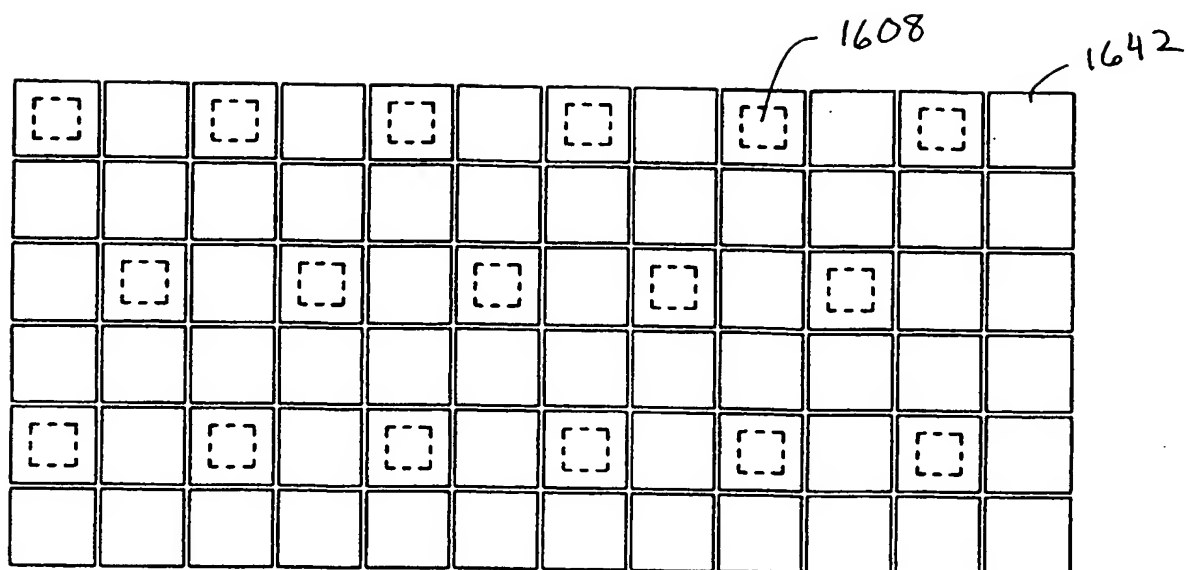


Fig. 17a

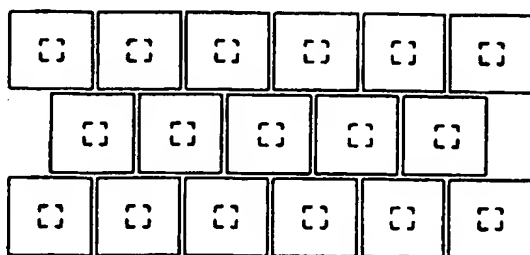


Fig. 17b

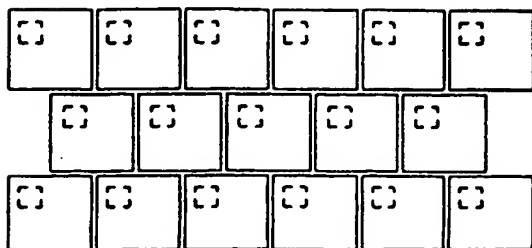


Fig. 17c

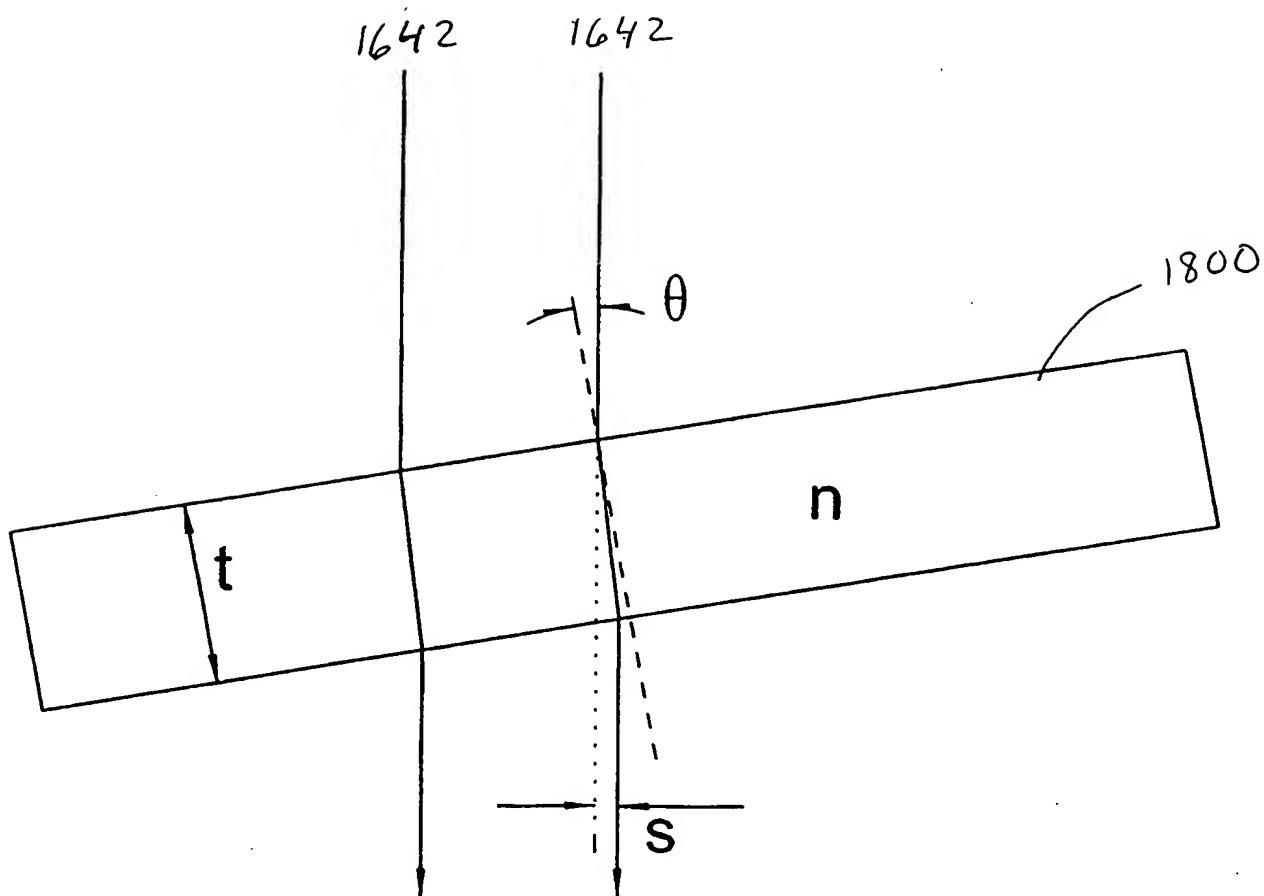


Fig. 18

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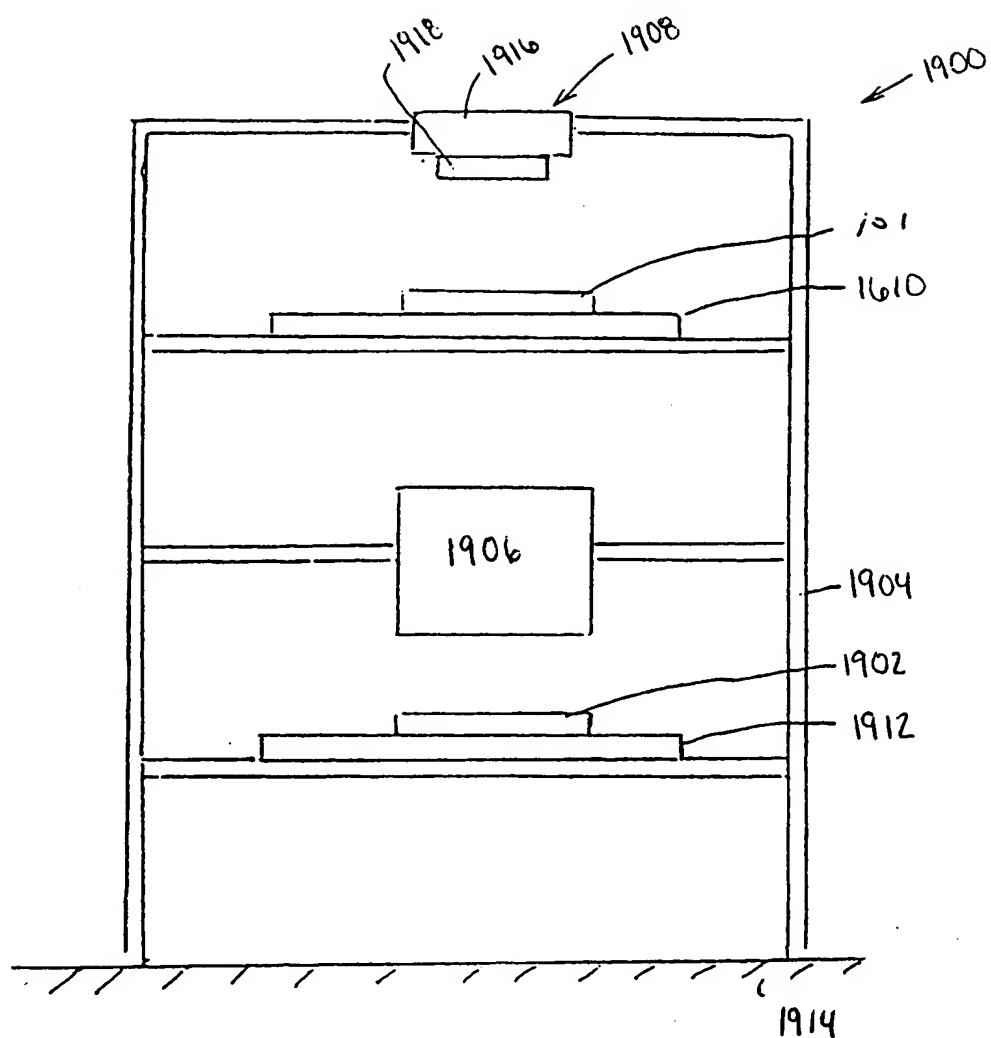


Fig 19

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